

## Scalable methodology for the direct synthesis of atomically thin WS<sub>2</sub> films

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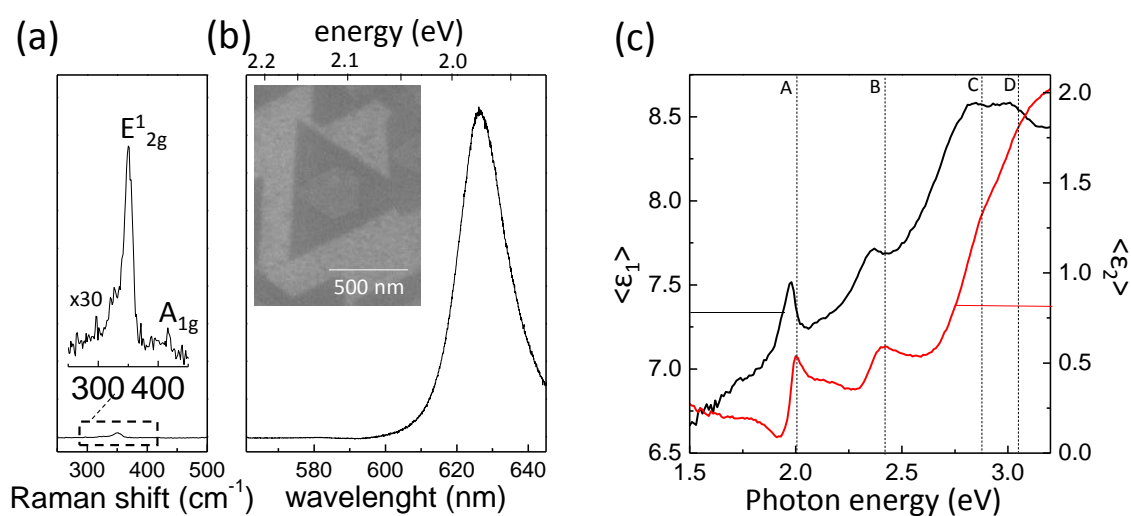
### Abstract

Tungsten disulfide (WS<sub>2</sub>) in the monolayer form is a promising 2D material for the next generation of optoelectronic devices due to its direct bandgap in the visible [1]. However, the development of such technologies needs scalable synthesis processes able to provide WS<sub>2</sub> deposition with full control in terms of structural quality, thickness and, hence, optical properties.

In this contribution, we show the flexibility of a pure chemical methodology for depositing mono and few layer WS<sub>2</sub> films with defined layer structures on different substrates including SiO<sub>2</sub>, Si, Al<sub>2</sub>O<sub>3</sub>, CVD- and epitaxial-graphene (van der Waals heterostructures). This CVD technique uses tungsten hexacarbonyl (W(CO)<sub>6</sub>) and sulfur (S) as precursors and is based on a single step chemical mechanism  $W(CO)_6 + S_2 \rightarrow WS_2 + 6CO$  which allows a good control in the material growth (especially on the large area) compared with more traditional two step processes based on the metal oxide physical deposition and subsequent sulfurization [2]. A full chemical (Raman, EDS), structural (SEM, AFM) and optical characterization (photoluminescence and spectroscopic ellipsometry) of deposited WS<sub>2</sub> films is provided to give further insight to the optical response of WS<sub>2</sub> exciton system and its dependence on WS<sub>2</sub> films structural quality and interface nature, e.g. presence of an epitaxial relationship with the substrate or occurrence of charge transfer processes.

### References

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[2] G. V. Bianco, M. Losurdo, M. M. Giangregorio, A. Sacchetti, P. Prete, N. Lovergine, P. Capezzuto, G. Bruno, *RSC Advances*, **5** (2015) 98700.



**Figure.** (a) Raman and (b) photoluminescence spectra (in the same intensity scale) of WS<sub>2</sub> film deposited on SiO<sub>2</sub> substrate (SEM image in the inset). (c) Ellipsometric spectra of the imaginary (<math>\langle \epsilon\_1 \rangle</math>) and real part (<math>\langle \epsilon\_2 \rangle</math>) of the pseudodielectric function ( $\epsilon = \langle \epsilon_1 \rangle + i \langle \epsilon_2 \rangle$ ) of WS<sub>2</sub> film on epitaxial graphene